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U.S. Patent Application No.: Unknown

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IN THE ABSTRACT:

Please replace the Abstract of the Disclosure originally filed with the above-identified patent application with the following new Abstract of the Disclosure:

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ABSTRACT OF THE DISCLOSURE

A compact, highly sensitive acceleration sensor that is not affected by factors other than acceleration, such as a change in temperature, includes a bimorph acceleration-sensor element including first and second resonators and attached to opposite sides of a base plate with respect to a direction in which acceleration is applied. One longitudinal end or both longitudinal ends of the acceleration-sensor element is/are fixed such that the resonators bend in the same direction in response to the acceleration. Changes in frequency or changes in impedance in the resonators caused by the bending of the acceleration-sensor element are differentially detected in order to detect the acceleration. The acceleration-sensor element is bendable about a central bending plane N1 in response to the acceleration, the central bending plane N1 being positioned at a central portion of the base plate with respect to the application direction of acceleration. Electrodes are disposed on main surfaces of the resonators, the main surfaces being substantially perpendicular to the application direction of acceleration. The height H₁ of the resonators in a direction that is substantially perpendicular to the application direction of acceleration is smaller than the height H₂ of the base plate in the direction that is substantially perpendicular to the application direction of acceleration.